

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

ATTN: **Mail Stop PCT**

Application No.: 10/594,458

Docket No.: 129546

Filed: September 26, 2006

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER

NOTIFICATION OF ACCEPTANCE AND FILING RECEIPT STATUS REQUEST

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The above-captioned patent application entered the National Phase on September 26, 2006. The 35 U.S.C. 371 requirements were completed on September 26, 2006.

The original Notification of Acceptance and Filing Receipt have not yet been received. It is respectfully requested that the original Notification of Acceptance and Filing Receipt be immediately forwarded to the attorneys of record at the address set forth below.

If there are any questions regarding this matter, please contact the undersigned at the telephone number set forth below.

Respectfully submitted,



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Date: February 14, 2007

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